

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kie Y. Ahn et al.

Title: LANTHANIDE DOPED TiO_x DIELECTRIC FILMS

Docket No.: 1303.070US2

Filed: February 27, 2004

Examiner: Douglas M. Menz

Serial No.: 10/789,044

Due Date: February 3, 2006

Group Art Unit: 2891



MS AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

- Return postcard.
- Amendment and Response Under 37 CFR 1.116--Expedited Procedure (13 pgs.).
- Communication Concerning Related Applications (2 pgs.).

If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.
Customer Number 21186

By: David R. Cochran
Atty: David R. Cochran
Reg. No. 46,632

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: MS AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 3 day of January, 2006.

Name

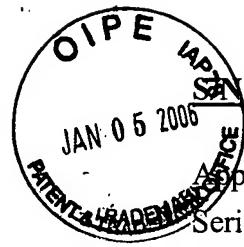
KACIA LEE

Signature

Kacia Lee

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

(GENERAL)



10/789,044

PATENTIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Serial No.: 10/789,044 Group Art Unit: 2891
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Title: LANTHANIDE DOPED TIOX DIELECTRIC FILMS

COMMUNICATION CONCERNING RELATED APPLICATION(S)

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Applicants would like to bring to the Examiner's attention the following related application(s) in the above-identified patent application:

<u>Serial/Patent No.</u>	<u>Filing Date/Issue Date</u>	<u>Attorney Docket</u>	<u>Title</u>
11/215451	August 29, 2005	1303.048US2	SYSTEMS AND APPARATUS FOR ATOMIC-LAYER DEPOSITION
11/189075	July 25, 2005	1303.148US1	MAGNESIUM TITANIUM OXIDE FILMS
11/215412	August 29, 2005	1303.121US2	RUTHENIUM GATE FOR A LANTHANIDE OXIDE DIELECTRIC LAYER
11/213013	August 26, 2005	1303.090US2	ATOMIC LAYER DEPOSITED DIELECTRIC LAYERS
11/212306	August 26, 2005	1303.097US2	ATOMIC LAYER DEPOSITED ZIRCONIUM TITANIUM OXIDE FILMS
11/204745	August 16, 2005	1303.044US3	EVAPORATION OF Y-Si-O FILMS FOR MEDIUM-k DIELECTRICS
11/214693	August 29, 2005	1303.082US3	ATOMIC LAYER DEPOSITED Zr-Sn-Ti-O FILMS USING TiI4

Continuations and divisionals may be later filed on the cases listed above, or cited to the Examiner in any previous Communication Concerning Related Applications. Applicants request that the Examiner review all continuations and divisionals of the above-listed or previously-cited patent applications before allowing the claims of the present patent application.

Respectfully submitted,

KIE Y. AHN ET AL.

By Applicants' Representatives,

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Date 3 January 2006 By _____

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Name _____

KACIA LEE

Signature _____

